



PATENT APPLICATION

**RESPONSE UNDER 37 CFR §1.114
EXPEDITED PROCEDURE
TECHNOLOGY CENTER ART UNIT 1763**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Kazuo ICHIKAWA et al.

Group Art Unit: 1763

Application No.: 09/670,877

Examiner: R. ZERVIGON

Filed: September 27, 2000

Docket No.: 107469

For: CVD SYSTEM AND SUBSTRATE CLEANING METHOD

AMENDMENT UNDER 37 CFR §1.114

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In reply to the September 29, 2005 Office Action, and in view of the attached Request
for Continued Examination, please consider the following:

Amendments to the Claims as reflected in the listing of claims; and

Remarks.